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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: ATTN: BOX RCE

Yoshio YANASE et al.

: Confirmation No. 6344

Serial No. 09/856,982

: Atty Docket No. 2001\_0615A

Filed May 30, 2001

: Group Art Unit 2877

METHOD FOR INSPECTING  
SEMICONDUCTOR WAFER SURFACE

: Examiner Sang H. Nguyen

**PATENT OFFICE FEE TRANSMITTAL FORM**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Attached hereto is a check in the amount of \$1,190.00 to cover Patent Office fees relating to filing the following attached papers:

Request for Continued Examination (RCE) ..... \$770.00

Petition for Extension of Time ..... \$420.00

A duplicate copy of this paper is being submitted for use in the Accounting Division, Office of Finance.

*The Commissioner is authorized to charge any deficiency or to credit any overpayment associated with this communication to Deposit Account No. 23-0975, with the EXCEPTION of deficiencies in fees for multiple dependent claims in new applications.*

Respectfully submitted,

Yoshio YANASE et al.

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[Check No. 58460]  
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